

USER BILIPLIERSS

GHALLANGES:

CHIPACCESS WITHOUT DAMAGE

SAFE, FAST AND REPETABLE PROCESS



SQUID/GIIR SAIMPLE PREPARATION

Goal:

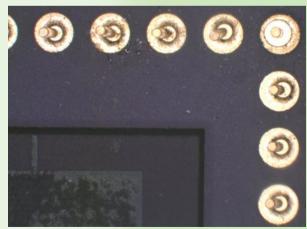
Remove nearly all molding compound above the die down to 100μ m thickness to allow SQUID investigations.

Benefits:

Safe, fast and repetable process.

Very helpfull when some package components are not chemical compatible.





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DIEPHOLE BENOVIL

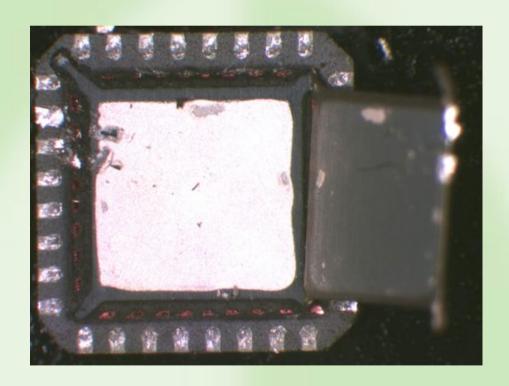
Goal:

Remove fastly die paddle to obtain backside access.

Benefits:

Fast and repetable process. No mechanical scratch on die backside.

Necessary to remove attach glue with acetone.





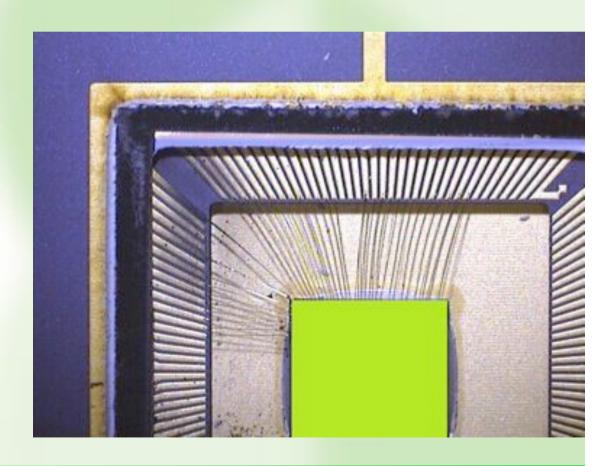
Goal:

Remove fastly glass cover.

Benefits:

Safe, fast and repetable process. No thermal stress on sample.

Necessary to clean sample with a solvent (vaporised glue).







Laser decapsulation: Plastic etching down to passive die backside (silicon).



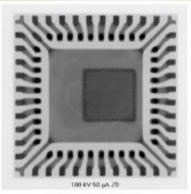
Plasma etching: Silicon etching on passive de backside.



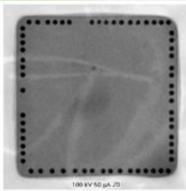
Wet & dry etching, down to underfill: Plasma etching => delectrics. Alu etch == metals levels.



Chemical decapsulation: Undefil etching.



Xrays analysis – global view: No visible damage on 1rd & 2rd interconnects.

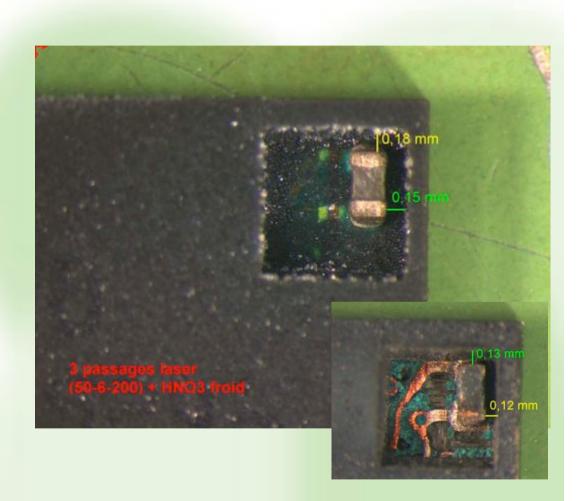


Xrays analysis – zoom on active die: No visible damage on 1⁵⁶ & 2⁵⁶ interconnects.

CONCLUSION: the sample was successfully prepared without removing PICS die and connections of active die to Leads.
This new method was improved during trials and test and is now operational.









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